[redacted]449

PATENTS AND OTHER ITEMS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT

(Use several sheets if necessary)

ATTY. DOCKET NO.	SERIAL NO.
02578.0006.US00	09/611,219
APPLICANT: Scott A. Chalmers, et al.	
FILING DATE: July 6, 2000	**GROUP:** 2877

OIPE
OCT 17 2000
PATENT & TRADEMARK OFFICE

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE
[redacted]	AA	5,436,725	07/25/95	Ledger	356	357	10/12/93

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION YES	TRANSLATION NO
[redacted]	AB	EP 0 644 399 A2	22.03.1995	Europe (Dainippon Screen Mfg. Co. Ltd.)				
[redacted]	AC	EP 0 663 265 A1	19.07.1995	Europe (International Business Machines Corporation)				

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

[redacted]	AD	Jones, G.R. et al., *Chromatic Interferometry for an Intelligent Plasma Processing System*, **MEASUREMENT SCIENCE & TECHNOLOGY**, Vol. 5, No. 6, June 1994 (1994-06), Pages 639-647, XP 000456344; Bristol, GB.
[redacted]	AE	Lange, V. et al., *Reflexionsinterferometrie zur Kontrolle dünner Silizium-Membranen*, **TECHNISCHES MESSEN**, Vol. 61, No. 9, September, 1994 (1994-09), pages 346-351, XP000465894, pages 346-351, figures 1-4
[redacted]	AF	***ImSpector*** Imaging Spectrograph brochure including specifications, **Spectral Imaging Ltd.**, Oulu, Finland, (3 pages)
[redacted]	AG	CCD Detectors, **Optical Systems Division**, retrieved on-line 6/21/00, (3 pages)
[redacted]	AH	*Advanced Thin Film Measurements – About thin Film,* **Filmetrics,** retrieved on-line 6/21/00; pages 1-6
[redacted]	AI	*Advanced Thin Film Measurements – Operation*, **Filmetrics,** retrieved on-line 6/21/00; pages 1-2
[redacted]	AJ	*Advanced Thin Film Measurements – PTFEON Data*, **Filmetrics,** retrieved on-line 6/21/00; (1 page)
[redacted]	AK	*Advanced Thin Film Measurements – faq*, **Filmetrics,** retrieved on-line 6/21/00; (2 pages)

RECEIVED
OCT 19 2001
TC 2800 MAIL ROOM

EXAMINER:	DATE CONSIDERED:
[redacted]	6/29/02

EXAMINER: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include a copy of this form with next communication to applicant

FORM PTO-1449	ATTY. DOCKET NO.	SERIAL NO.
LIST OF PATENTS AND OTHER ITEMS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT	02578.0006.US00	09/611,219
	APPLICANT: Scott A. Chalmers, et al.	
(Use several sheets if necessary)	FILING DATE: July 6, 2000	GROUP: 2877

OIPE JAN 24 2002 PATENT & TRADEMARK OFFICE

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE
[illegible]		4,555,767	11/26/85	Case et al.			10/28/92
[illegible]		5,747,813	05/05/98	Norton et al.			04/14/94

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION YES	TRANSLATION NO
[illegible]		EP 0 652 415 A1	05/10/95	(European) DE FR GB, IT, NL			X	

RECEIVED FEB 15 2002 TC 2800 MAIL ROOM

EXAMINER: [signature]	DATE CONSIDERED: 6/29/02

EXAMINER: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include a copy of this form with next communication to applicant